



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

July 1, 2003

Applicants : Bruce M. WARNES et al.

For : CHEMICAL VAPOR DEPOSITION APPARATUS AND METHOD

Serial No. : 09/950 012

Group: 1764

Filed : Sept. 10, 2001

Examiner: Leung

Confirmation No. 9232

Commissioner for Patents

P.O. Box 1450

Arlington, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

Please amend the above application as follows:

~~IN THE SPECIFICATION~~

~~Please amend page 12, lines 1-10 as follows:~~

provided on trays 28. The trays 28 include a central hole 28a having inner diameter about equal to the outer diameter of pipe or conduit 18 to receive same in manner that the trays 28 are symmetrically disposed about the pipe or conduit ~~26~~ 18. The trays 28, spacer walls 64, and baffles 66 are stacked atop one another and supported on a lowermost, laterally flange 18a of the pipe or conduit 18. The gas distribution pipe or conduit 18, trays 28, spacer walls 64 and baffles 66 thereby are arranged in fixed positions symmetrically about the central longitudinal axis of the coating chamber 20.